TANAKA et al. -- Appln. No. 08/522,085

a high-emissivity layer formed by a material having a high emissivity [is] provided on at least one of said internal surface of said sensor element and the surface of said heater;

wherein said high-emissivity layer provided on said internal surface of said sensor element has an emissivity of 0.3 or more, and said high-emissivity layer provided on said surface of said heater is 0.6 or more;

wherein a clearance is formed between the high-emissivity layer and the internal electrode, the clearance being 0.1 mm or more; and

a porosity of the high-emissivity layer being set to a predetermined value to keep a diffusion of air into the internal electrode and

said heater being made of non-oxide type ceramic.

6. (Amended) An oxygen concentration detector comprising:

a sensor element including a solid electrolyte and an external electrode[s] provided on an external surface thereof;

a heater provided adjacent to an internal surface of said sensor element; and

an electrode containing a material having a high emissivity is provided on said internal surface of said sensor element;

wherein said electrode provided on said internal surface of said sensor element has an emissivity of 0.3 or more;

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wherein a clearance is formed between the high-emissivity
layer and the internal electrode, the clearance being 0.1 mm or
more;

a porosity of the high-emissivity layer being set to a predetermined value to keep a diffusion of air into the internal electrode.

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9. (Amended) An oxygen concentration detector comprising: a sensor element including a solid electrolyte and external

a sensor element including a solid electrolyte and external internal electrodes provided on external and internal surfaces thereof, respectively;

a heater provided adjacent to said internal surface of said sensor element the heater being made of non-oxide type ceramic;

wherein said heater consists of one or more materials selected from a group consisting of silicon nitride, aluminum nitride[,] and silicon carbide [nitride].

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11. An oxygen concentration detector according to claim 9, wherein said material having [high emissivity] has an emissivity of 0.6 or more.

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12. (Amended) An oxygen concentration detector comprising:

a sensor element including a solid electrolyte and external
and internal electrodes provided on external and internal
surfaces thereof, respectively;

a heater provided adjacent to said internal surface of said sensor element;

wherein said internal electrode consists of a material having a high emissivity, and said external electrode consists of a material having an emissivity lower than the emissivity of said internal electrode; and

wherein a clearance is formed between the high-emissivity.

layer and the internal electrode, the clearance being 0.1 mm or more.

An oxygen concentration detector according to claim 12, wherein said internal electrode consists of platinum black or [and] ruthenium oxide.

An oxygen concentration detector according to claim wherein a [said] surface of said internal electrode facing [to] said external electrode consists of a material having an emissivity higher than the emissivity of said external electrode.

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16. (Amended) An oxygen concentration detector comprising:

a sensor element including a solid electrolyte and external and internal electrodes provided on external and internal surfaces thereof, respectively;

a heater provided adjacent to an internal surface of said sensor element;

wherein at least said surface of said internal electrode consists of a material having a high emissivity, and a layer consisting of a material having an emissivity lower than the emissivity of said internal electrode is provided as an outermost layer of said sensor element; and

wherein a clearance is formed between the high-emissivitylayer and the internal electrode, the clearance being 0.1 mm or more.

Kindly add the following new claims:

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--18. An oxygen concentration detector according to claim 1, wherein the thickness of the high-emissivity layer is in the range of 5-20 μm .

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19. An oxygen concentration detector according to claim 1, wherein the porosity of the high-emissivity layer is 10% or more.--

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